

# Hall Effect Measurements for Semiconductor and Other Material Characterization

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Keithley Instruments, Inc.

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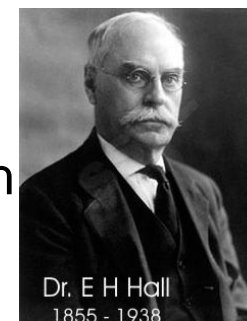
# Seminar Overview

- What are Hall effect measurements?
- Industry trends driving the need for Hall effect measurements
- Key considerations when selecting equipment for Hall effect measurements
- Measurement techniques



# Hall Effect Measurement Overview

- A Hall effect measurement system is used to measure a material's electrical properties such as:
  - Carrier mobility ( $\mu$ ) and concentration ( $n$ )
  - Hall voltage ( $V_H$ )
  - Hall coefficient ( $R_H$ )
  - Resistivity ( $\rho$ )
  - Magnetoresistance ( $R_B$ )
  - Conductivity Type (N or P)
  - I-V curves (optionally)
- The Hall effect refers to the potential difference (Hall voltage) on the opposite sides of an electrical conductor through which an electric current is flowing, created by a magnetic field applied perpendicular to the current. Edwin Hall discovered this effect in 1879. [http://en.wikipedia.org/wiki/Hall\\_effect](http://en.wikipedia.org/wiki/Hall_effect)

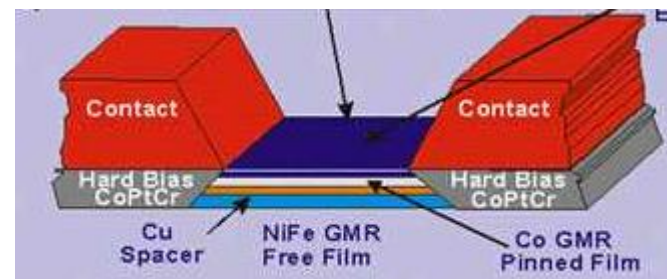


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# Materials Types

The Hall Effect is used to measure:

- Semiconductor materials such as Si, Ge
- Most compound semiconductor materials including pHEMTs, SiGe, SiC, GaAs, AlGaAs, InAs, InGaAs, InP, AlGaAs, and CdTe HgCdTe (including thin films for solar cell/photovoltaics)
- Organic semiconductors and nano-materials
- Low resistance materials including metals, transparent oxides, highly doped semiconductor materials, high temperature superconductors, dilute magnetic semiconductors, GMR/TMR materials, and graphene-based materials
- High resistance semiconductor materials including semi-insulating GaAs and GaN, and CdTe



# Why the Resurgence in People Doing Hall Effect? Some “Simple” Math...

$$I = \frac{V}{R} = \frac{V}{\frac{\rho L}{A}} = \frac{VA}{\rho L} = \frac{qn\mu VA}{L}$$

$I$  = Current (A)

$V$  = Voltage (V)

$R$  = Resistance of sample ( $\Omega$ )

$\rho$  = Resistivity of sample ( $\Omega$ -cm)

$L$  = length of sample (cm)

$A$  = cross sectional area  
of sample ( $\text{cm}^2$ )

For a doped semiconductor:

$$\rho = \frac{1}{qn\mu}$$

$q$  = Electron charge ( $\text{C}/\text{cm}^2$ )

$n$  = Carrier carrier concentration ( $\text{cm}^{-3}$ )

$\mu$  = Carrier mobility ( $\text{cm}^2/\text{Vs}$ )

# Why the Resurgence in People Doing Hall Effect? Some “Simple” Math...

$n$  = electron carrier density ( $\text{cm}^{-3}$ )

$\mu$  = electron mobility ( $\text{cm}^2/\text{Vs}$ )

$V$  = voltage applied (V)

$L$  = length of sample (cm)

$A$  = cross sectional area of sample ( $\text{cm}^2$ )

$$I = \frac{qn\mu VA}{L}$$

- To increase  $I$  (higher drive current, faster switching, etc.)
  - Increase voltage,  $V$ ,
  - Increase number of electrons,  $n$
  - Increase area of sample,  $A$
  - Increase mobility of electrons,  $\mu$

## The Goal: Maximizing Current Flow

$n$  = electron carrier density ( $\text{cm}^{-3}$ )

$\mu$  = electron mobility ( $\text{cm}^2/\text{Vs}$ )

$V$  = voltage applied (V)

$L$  = length of sample (cm)

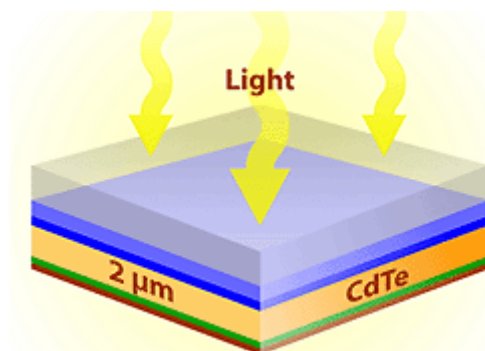
$A$  = cross sectional area of sample ( $\text{cm}^2$ )

$$I = \frac{qn\mu VA}{L}$$

- To increase  $I$  (higher drive current, faster switching, etc)
    - Increase voltage,  $V$
    - Increase number of electrons,  $n$
    - Increase area of sample,  $A$
    - Increase mobility of electrons,  $\mu$  ✓
- Becoming more difficult*

# Hall Effect Measurements are the Quantitative Tool for Determination of Mobility on New Materials

- Can no longer just keep shrinking devices to get performance
  - Moore's Law collides with photolithography limits
- Therefore, materials are no longer just Si
  - People adding Ge to Si to strain lattice to get higher mobility  $\mu$
- Materials are no longer bulk
  - Thin films like in CIGS solar cells
  - Single-atom layer materials, Graphene



- **HALL effect measurement derives  $\mu$**

$$I = \frac{qn\mu VA}{L}$$

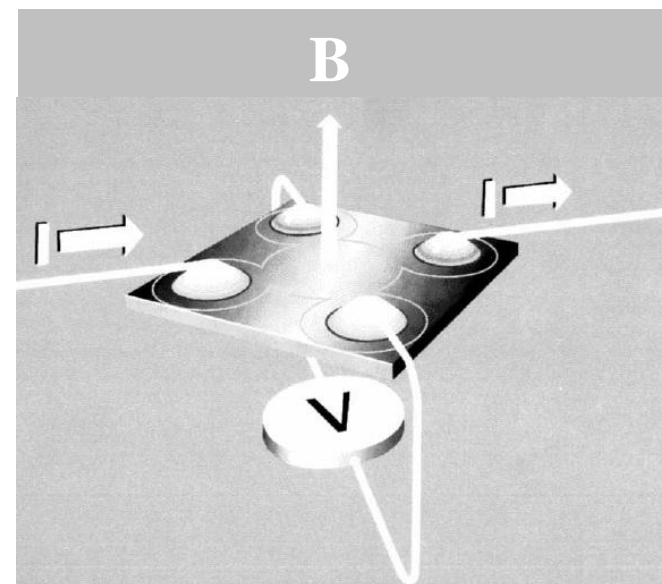
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# How to Measure Mobility, $\mu$ , Using Hall Effect Techniques Overview

- First measure Hall Voltage,  $V_H$ 
  - Force magnetic field  $B$
  - Source  $I$
  - Measure  $V_H$
  - $t$  is sample thickness
- Next, measure resistivity,  $\rho$ 
  - Use the van der Pauw technique
- Then calculate Hall mobility,  $\mu_H$ :

$$\mu_H = \frac{|V_H t|}{BI\rho}$$

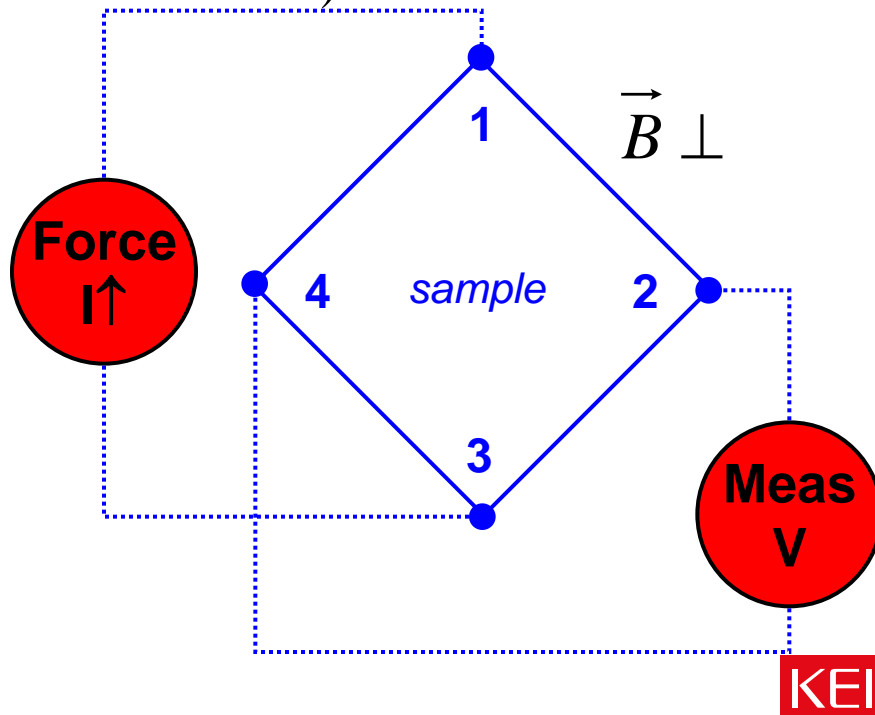


# How to Measure Mobility, $\mu$ , Using Hall Effect Techniques

## Measurement Configuration

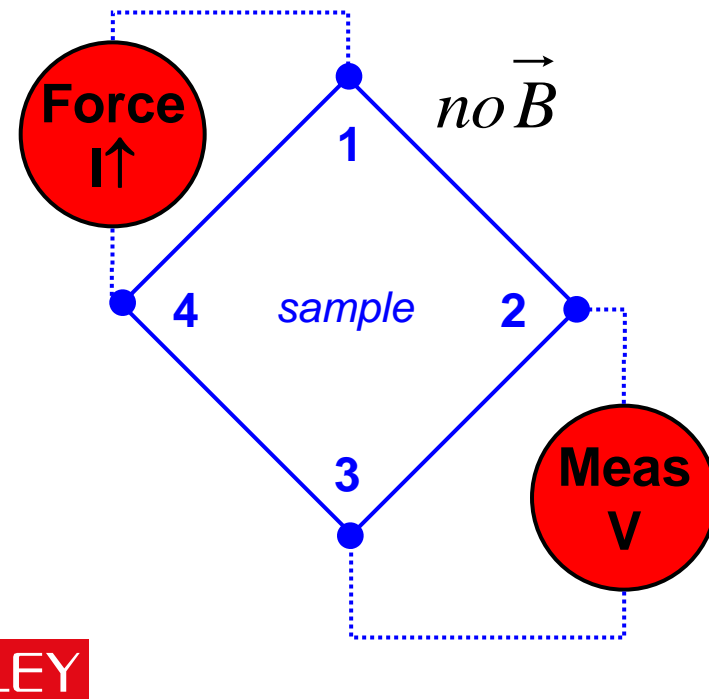
### Hall Effect:

- Force I on **opposite** nodes
- Meas V on the other opposite nodes
  - V typically  $\sim$  nV – V (typically uV-mV)



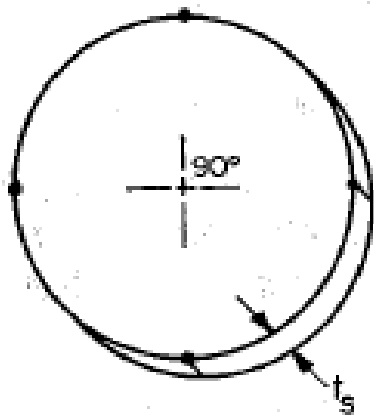
### van der Pauw resistivity:

- Force I on **adjacent** nodes
- Meas V on the opposing adjacent nodes
  - V should be  $< 5V$ , typically mV
- Gives  $\rho$  so that  $\mu$  can be calculated

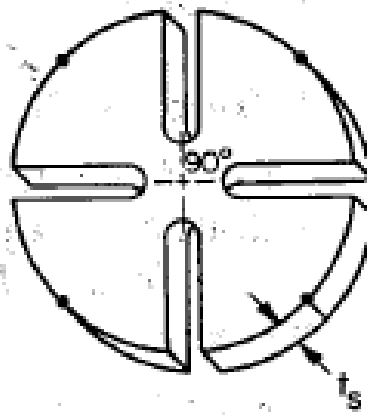


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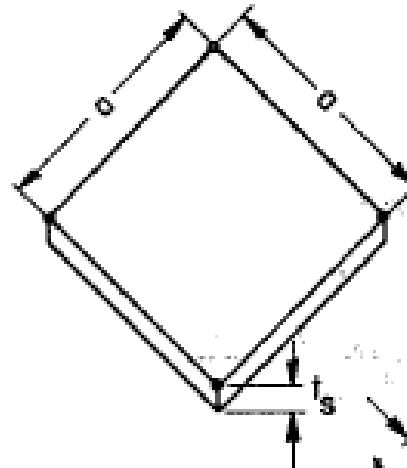
# ASTM Recommended Sample Specimens for Hall Effect and van der Pauw Measurements



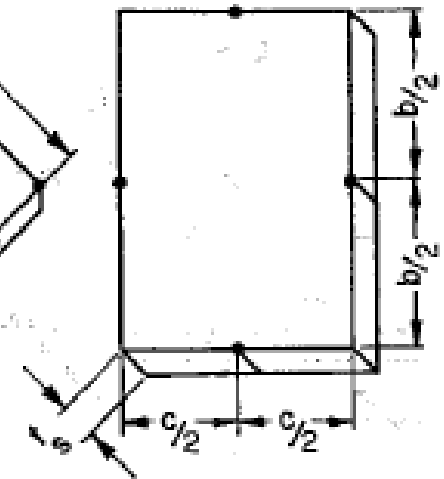
Circle



Clover Leaf



Square



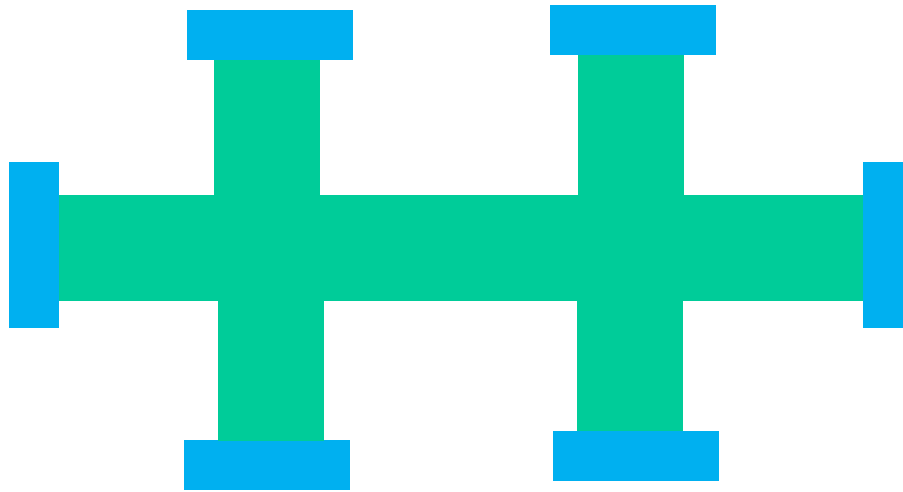
Rectangle

Recommended sample thickness is  $\leq 0.1\text{cm}$

Reference: ASTM F76

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# Additional ASTM Sample Geometries Bridge-Type or Hall Bar Configurations

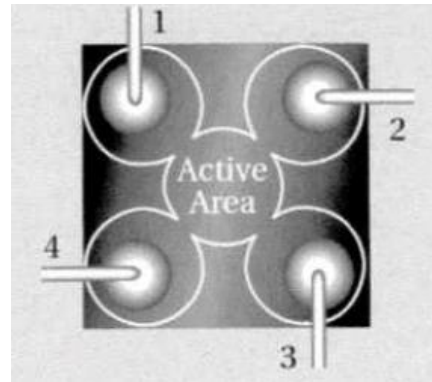


Typical configuration used by graphene researchers

Reference: ASTM F76

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# Good Sample Preparation Technique Ensures Good Measurements



- Ohmic contact quality, symmetry, and size
- Sample uniformity
- Accurate knowledge of thickness
- Temperature uniformity
- Photoconductive and photovoltaic effects

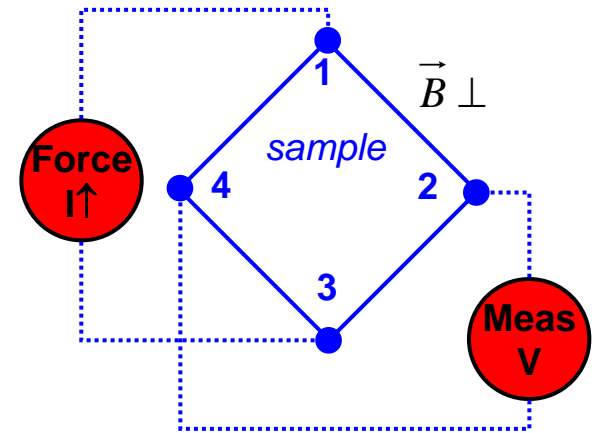
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# How to Measure Mobility, $\mu$ , Using Hall Effect Techniques

## Determining an Accurate $V_H$

[www.nist.gov/eeel/](http://www.nist.gov/eeel/)

1. Apply a Positive magnetic field B
2. Force a current  $I_{13}$  to leads 1 and 3 and measure  $V_{24P}$
3. Force a current  $I_{31}$  to leads 3 and 1 and measure  $V_{42P}$
4. Likewise, measure  $V_{13P}$  and  $V_{31P}$  with  $I_{42}$  and  $I_{24}$ , respectively
5. Reverse the magnetic field (Negative B)
6. Likewise, measure  $V_{24N}$ ,  $V_{42N}$ ,  $V_{13N}$ , and  $V_{31N}$  with  $I_{13}$ ,  $I_{31}$ ,  $I_{42}$ , and  $I_{24}$ , respectively
7. Calculate Hall voltage,  $V_H$



**Changing connections during Steps 4 & 6 → automate with a switch matrix**  
 Especially if sample is in a liquid nitrogen dewar

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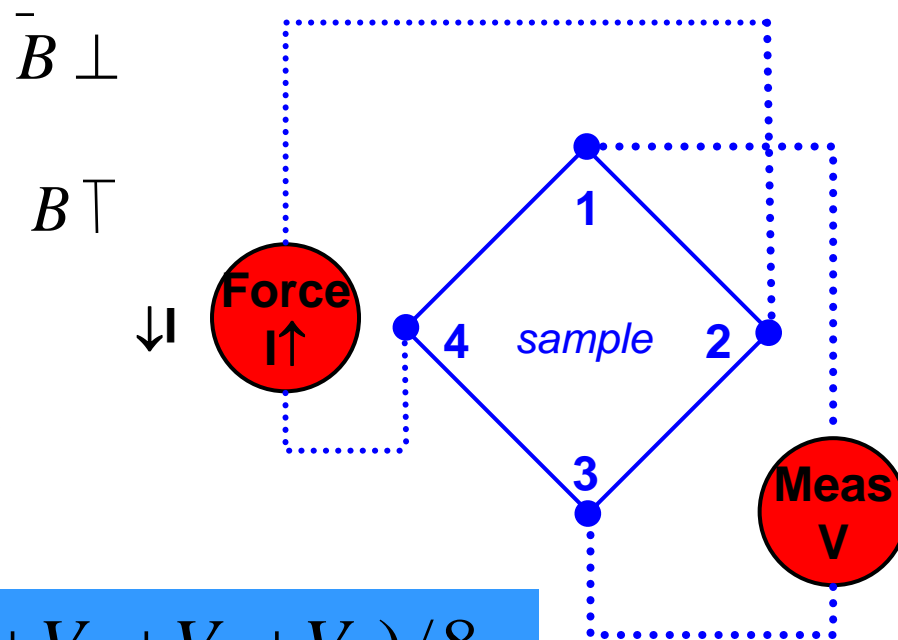
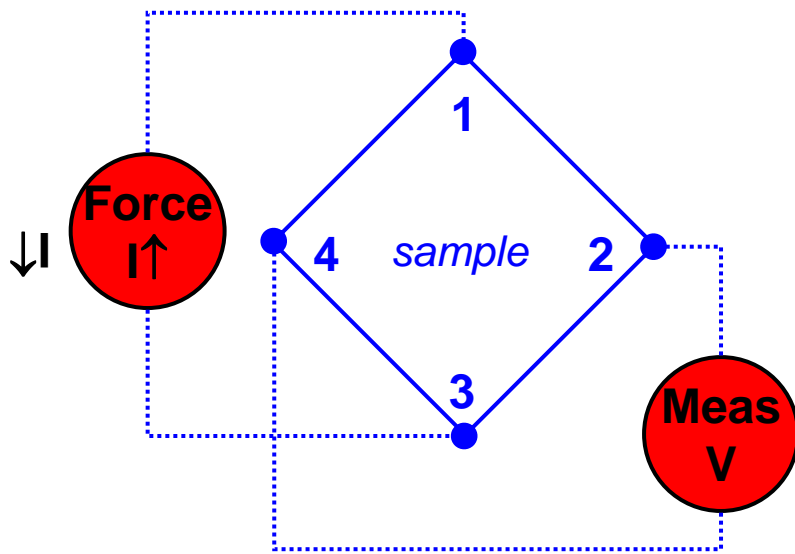
# Computing the Hall Voltage

$$V_C = V_{24P} - V_{24N}$$

$$V_D = V_{42P} - V_{42N}$$

$$V_E = V_{13P} - V_{13N}$$

$$V_F = V_{31P} - V_{31N}$$



$$V_H = (V_C + V_D + V_E + V_F) / 8$$



# Computing Resistivity, $\rho$ , with the van der Pauw Measurement

$$R_{14,23} = V_{23} / I_{14}$$

$$R_{23,14} = V_{14} / I_{23}$$

$$R_{43,12} = V_{12} / I_{43}$$

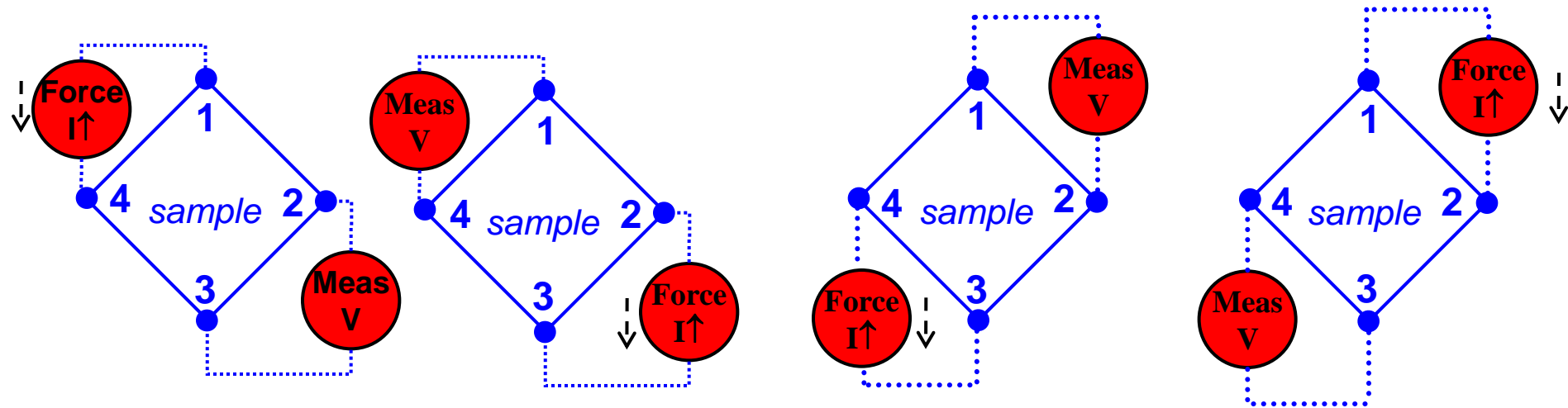
$$R_{12,43} = V_{43} / I_{12}$$

$$R_{41,32} = V_{32} / I_{41}$$

$$R_{32,41} = V_{41} / I_{32}$$

$$R_{34,21} = V_{21} / I_{34}$$

$$R_{21,43} = V_{34} / I_{21}$$



$$R_A = (R_{21,34} + R_{12,43} + R_{43,12} + R_{34,21}) / 4$$

$$R_B = (R_{32,41} + R_{23,14} + R_{14,23} + R_{41,32}) / 4$$

$$e^{(-\pi R_A / R_S)} + e^{(-\pi R_B / R_S)} = 1$$

$$\rho = R_S \cdot t$$

If  $R_A = R_B = R$

then  $R_S = \frac{\pi}{\ln 2} R$



# Final Computation to Determine Hall Mobility

$$\mu_H = \frac{|V_H t|}{BI\rho}$$

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# Hall Effect Equipment List

## Measurement Equipment

- Constant-current source, magnitude depends on sample resistance
  - Low resistance material (mA to A)
  - Semi-insulating GaAs,  $\rho \sim 10^7 \Omega \cdot \text{cm}$ , a range as low as 1nA is needed
  - High resistance (intrinsic semiconductors) (nA to pA)
- Voltmeter covering 1 $\mu$ V to 100V
  - Required range depends on material resistivity
  - High resistivity materials may need ultra-high input Z or differential measurement
- Optional:
  - Switch matrix to eliminate manual connection and disconnection
  - Temperature measurement instrument
    - Sample temperature-measuring probe (resolution of 0.1°C for high accuracy work)

# Hall Effect Equipment List

## Magnetic Field Generation, Sample Holder, and Environmental Control

- Magnet:
  - Fixed/permanent magnet or electromagnet
    - 500 to 5000 gauss
- Prober with manipulators and probe tips
- If doing temperature studies:
  - Appropriate prober chuck or oven
  - Temperature controller
  - Cryostat for holding samples if low-temperature



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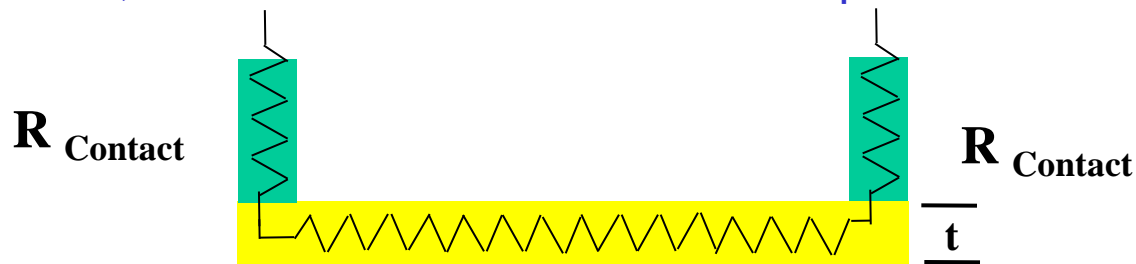
# Other Equipment Needed

## Other Measurements

- A more general research lab will want Hall effect and more:
  - Collinear resistivity measurements
  - Full I-V sweeps
  - C-V measurements
  - Transient response studies
- So “other equipment” list may include complementary equipment (hardware and software) not just for Hall effect but related measurements

# Selecting the Correct Measurement Equipment Based on Sample's Total Resistance

- Total Resistance is Sample Resistance + Contact Resistance
  - Sample Resistance → value is primarily based on sample's resistivity,  $\rho$ , & sample's thickness,  $t$
  - For square sample, sample resistance  $R = \rho/t$
- Contact resistance at metal-semiconductor interface (some nominal approximations):
  - GaAs : Contact resistance  $\sim 1000 * \text{sample resistance}$
  - For Si, Contact resistance  $\sim 300 * \text{sample resistance}$



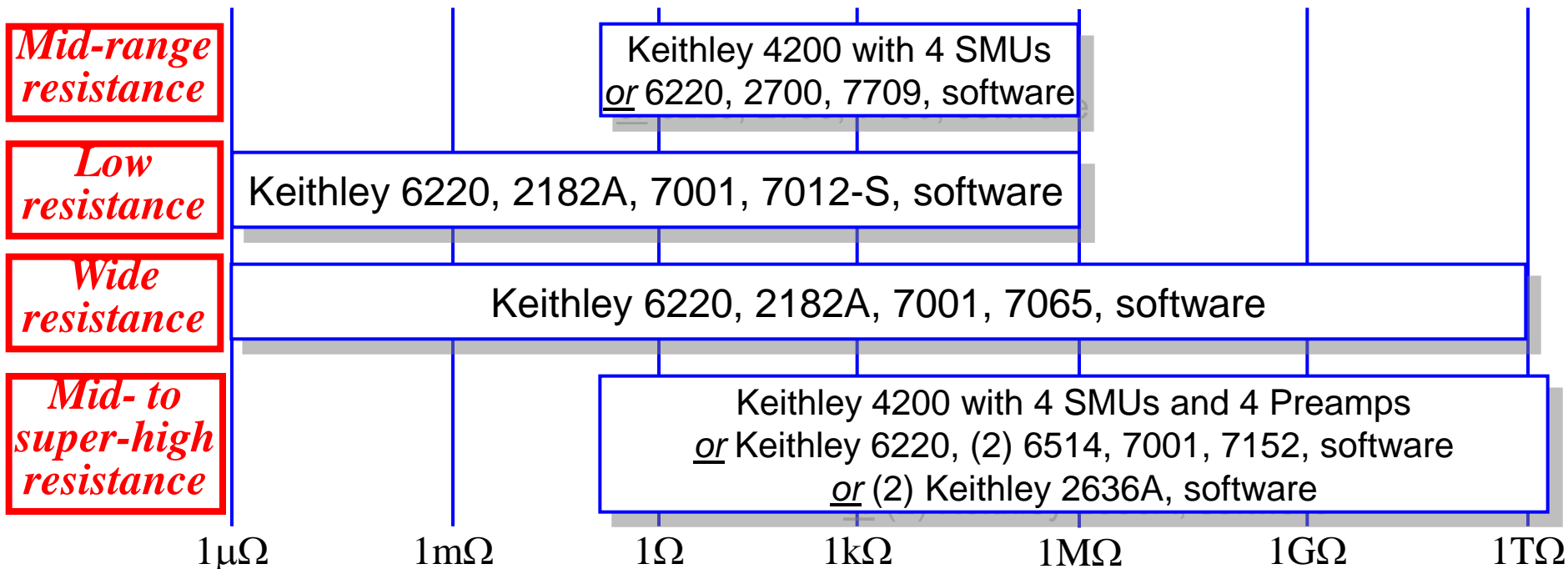
$$R_{\text{sample}} = \rho/t$$

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# Selecting the Correct Measurement Equipment Based on Sample's Total Resistance

- Representative ranges:
  - Mid-range resistance
    - Typically: Nominally doped Si or Ge ( $\sim 10^{15} \text{ cm}^{-3}$ ); Si photovoltaics; pHEMTS; ITO
  - Low resistance
    - Typically metals, highly doped Si or Ge ( $> 10^{17} \text{ cm}^{-3}$ ); SiGe; superconductors; GMR/TMR
  - Low-to-high (wide range) resistance
    - Typically thin film photovoltaics like CIGS, CdTe, HgCdTe
  - Mid- to super-high resistance
    - Typically GaAs, GaN, InP, InGaAs, AlGaAs, SiC, semi-insulating Si or CdTe

# Overview of Instrumentation Solutions



Sample Resistance ( $\Omega$ )

(actual selection depends on Total Resistance = Sample Resistance + Contact Resistance)

Sample Resistance  $\approx \rho/t$



# Hall Effect Measurement Equipment



- **Mid-range resistance**

- **100 mΩ to 1 MΩ**

- Typically: Nominally doped Si or Ge ( $\sim 10^{15} \text{ cm}^{-3}$ ); Si photovoltaics; pHEMTs; ITO

- Low resistance

- Low-to-high (wide range) resistance

- Mid- to super-high resistance

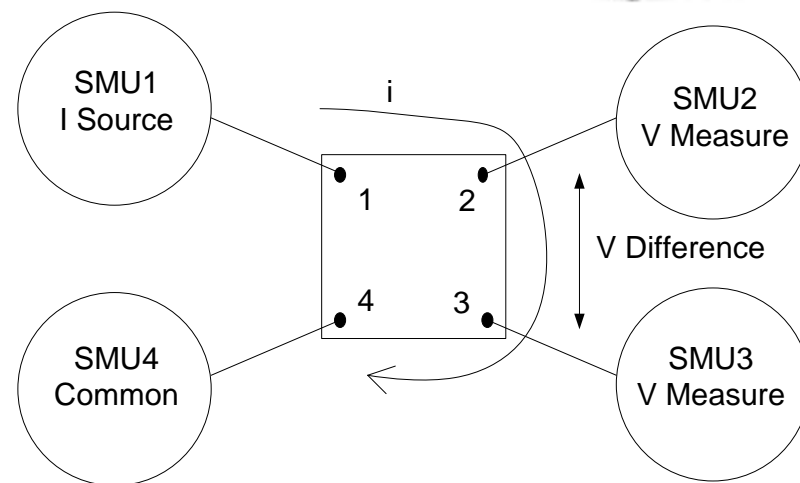
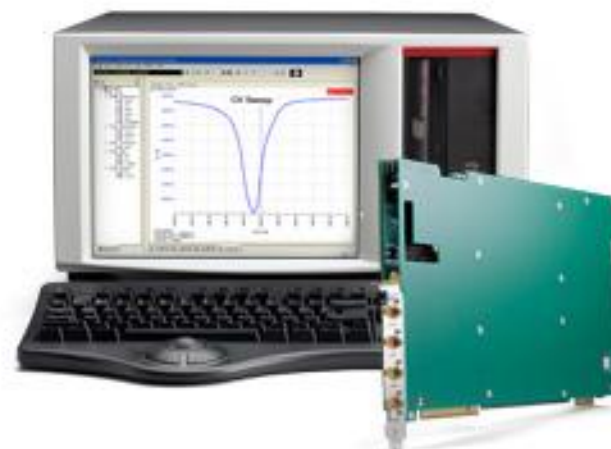


## Mid-Range Resistance Measurements (100mΩ to 1MΩ)

- Option 1
  - 1 Model 4200-Semiconductor Characterization System with 4 Source-Measure Units
    - Includes turn-key software for electrical resistivity measurement
- Option 2
  - 1 Model 6220 Precision Current Source
  - 1 Model 2700 DMM
  - 1 Model 7709 6x8 Matrix Switch Card
    - Can do 2 samples at a time

# Mid-Range Resistance Measurements (100mΩ to 1MΩ) (cont'd)

- Option 1: 4200-SCS with 4 Source-Measure Units (SMUs)
  - 4200 includes project to measure van der Pauw resistivity
  - Project changes functions of SMU to be either current source or voltmeter
    - This eliminates the need for a switch matrix

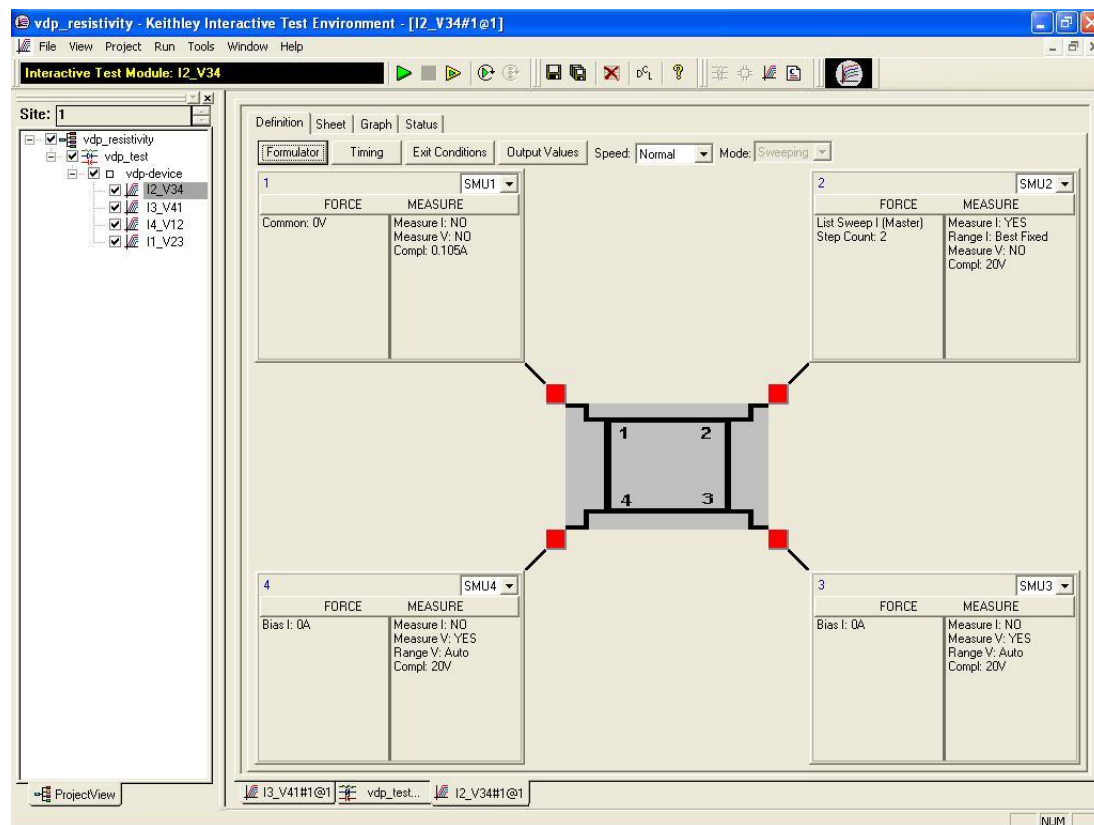


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# Mid-Range Resistance Measurements (100mΩ to 1MΩ) (cont'd)

## • Option 1: 4200-SCS with 4 SMUs

- Resistivity derived by taking eight current-voltage measurements around periphery of sample
- The 4200 can also be used to make I-V and C-V measurements on devices



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# Mid-Range Resistance Measurements (100mΩ to 1MΩ) (cont'd)

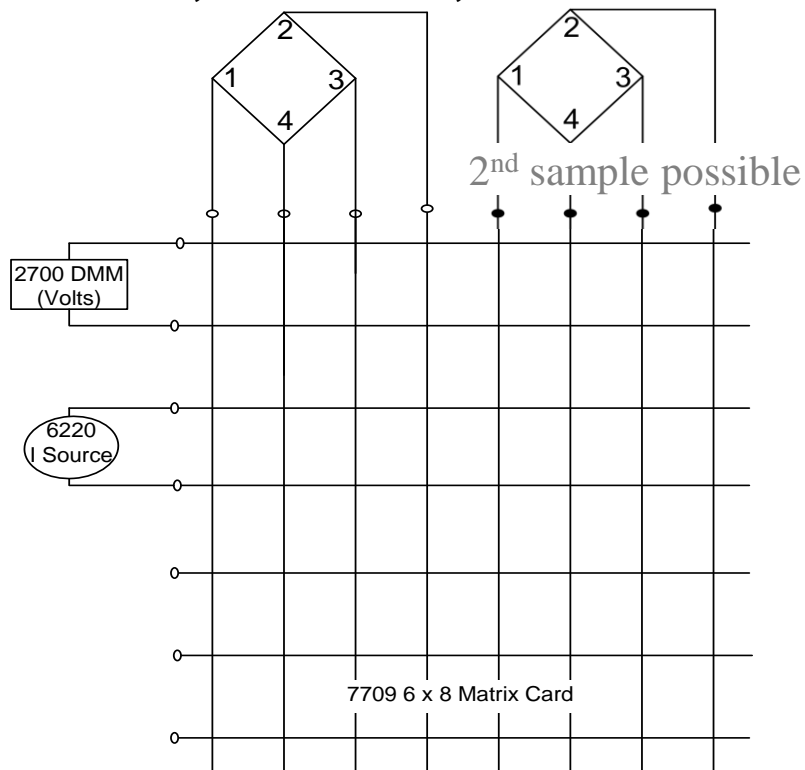
- Option 2 connection scheme
  - 6220 Current Source, 2700 DMM, 7709 Matrix Card



DMM + Switch Module



Current Source



# Hall Effect Measurement Equipment

- Mid-range resistance



- **Low resistance**

- 1  $\mu\Omega$  to 1  $M\Omega$

- Typically metals, highly doped Si or Ge ( $>10^{17} \text{ cm}^{-3}$ ); SiGe; superconductors; GMR/TMR

- **Challenge here is that the low-resistance sample results in very low measured V**

- Need nV measurements
- Force higher currents to allow higher measured voltage

- Low-to-high (wide range) resistance

- Mid- to super-high resistance

# Low Resistance Measurements ( $1\mu\Omega$ to $1M\Omega$ )

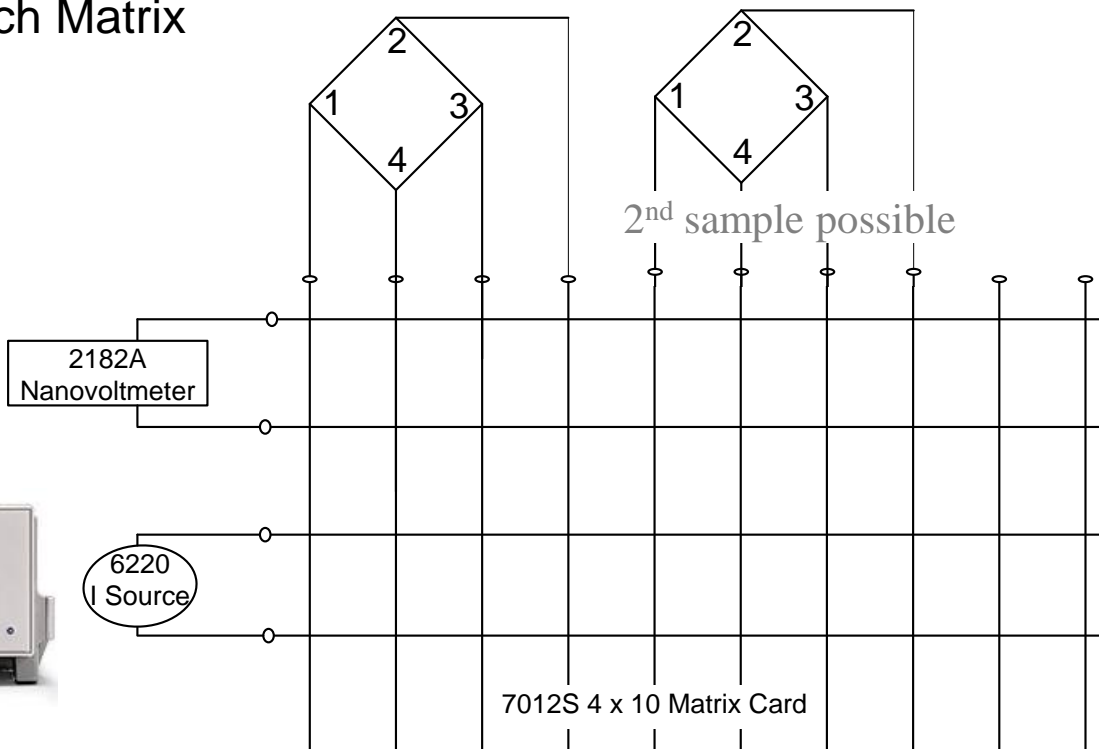
- Connection scheme
  - 6220 Current Source, 2182A Nanovoltmeter, 7001/7012S 4x10 Switch Matrix



Nanovoltmeter



Current Source



Switch Mainframe



# Techniques for Eliminating Errors when Making Low Voltage Measurements

- Minimize sources of thermoelectric voltages
  - Whenever possible use the same materials in all connections
  - Use all copper connections and copper wire
  - Reverse current source polarity and average readings
- Allow test equipment to warm up and reach thermal equilibrium
- Minimize temperature gradients across the sample
- Eliminate ground loops
- Shield the system

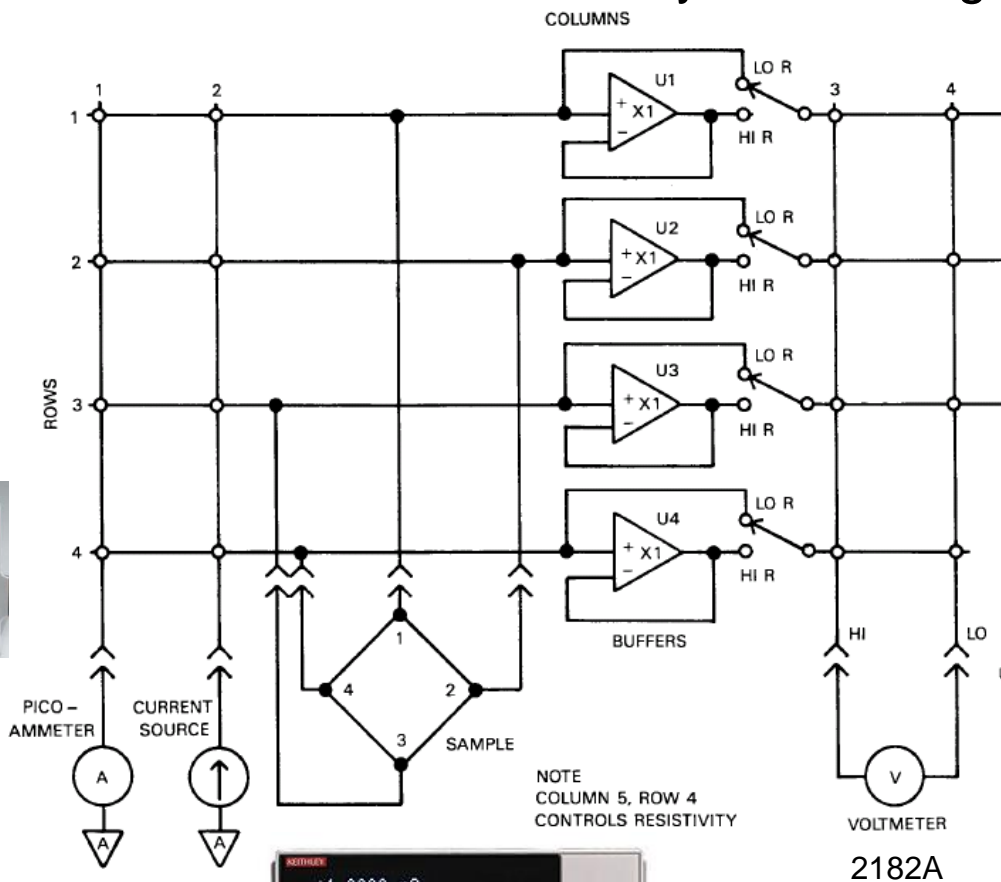
# Hall Effect Measurement Equipment

- Mid-range resistance
- Low resistance
-  **Low-to-high (wide range) resistance**
  - $1\mu\Omega$  to  $1T\Omega$ 
    - Typically thin film photovoltaics like CIGS, CdTe, HgCdTe, increasingly doped material
- Mid- to super-high resistance



# Wide-Range Resistance Measurements (1 $\mu\Omega$ to 1T $\Omega$ ) Instrument Setup (cont'd)

Model 7065 Hall Effect Card Based System Configuration:



Switch Mainframe



Picoammeter

6220  
Current Source



Nanovoltmeter

# Hall Effect Measurement Equipment

- Mid-range resistance
- Low resistance
- Low-to-high (wide range) resistance
-  **Mid- to super-high resistance**
  - **100mΩ to 10TΩ**
    - Typically GaAs, GaN, InP, InGaAs, AlGaAs, SiC, semi-insulating Si or CdTe
  - **Adds 1 more decade of high resistance compared to “Low-to-high resistance” configuration**

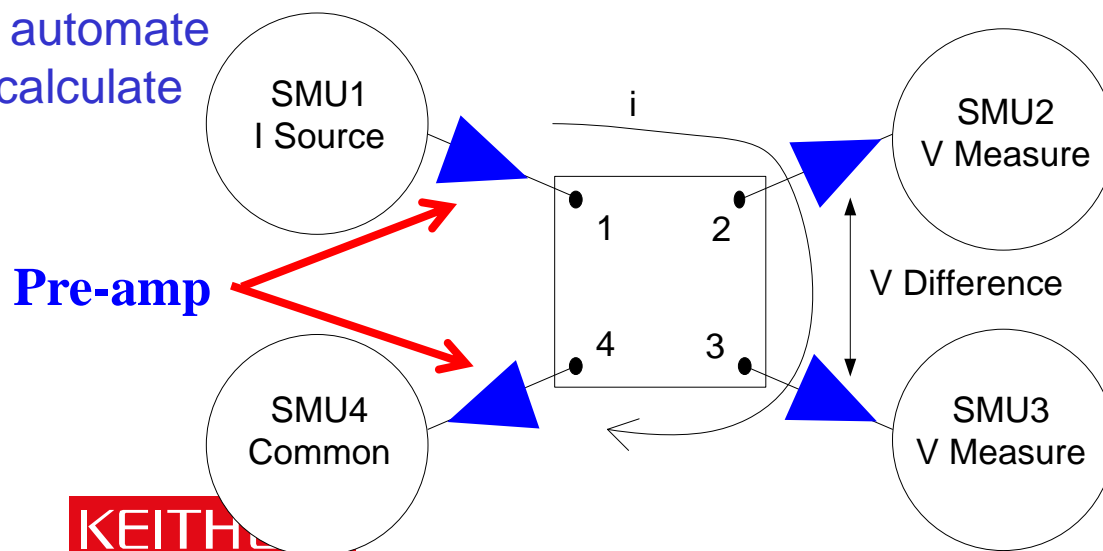
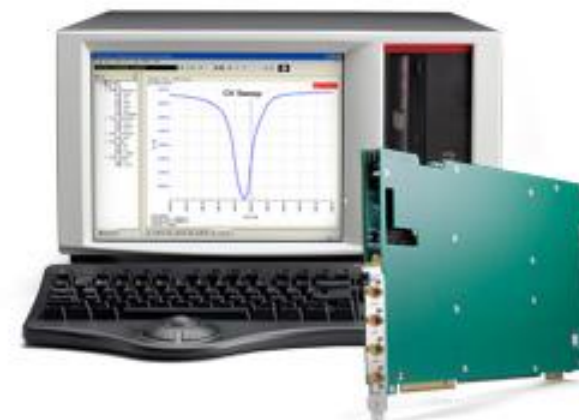
# Mid- to Super-High Resistance Measurements (100 mΩ to 10 TΩ)

- Option 1
  - 1 Model 4200-Semiconductor Characterization System with 4 Source-Measure Units (SMUs) and 4 preamps
    - Includes turn-key software for electrical resistivity
- Option 2
  - 1 Model 6220 Precision Current Source
  - 2 Model 6514 Electrometers
  - 1 Model 2000 DMM
  - 1 Model 7001 Switch Mainframe
  - 1 Model 7152 Low Current 4x5 Matrix Switch Card
- Option 3:
  - Use 2 x 2636A SourceMeter® Instruments

The logo consists of the word "KEITHLEY" in white, uppercase, sans-serif font, centered within a red rectangular background.

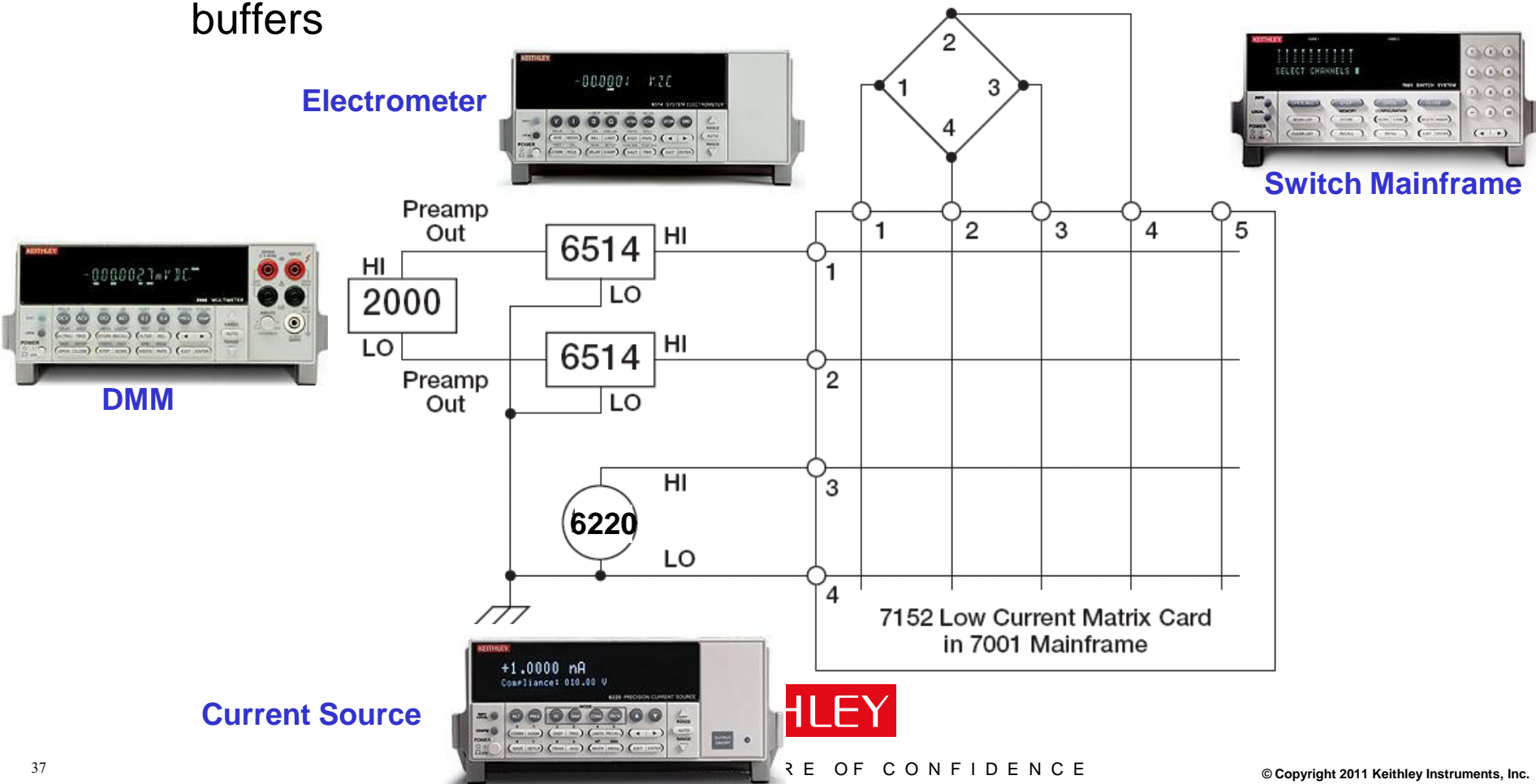
# Mid- to Super-High Resistance Measurements (100mΩ to 10TΩ)

- Option 1: Model 4200-SCS with 4 SMUs and 4 pre-amps
  - Input impedance  $>10^{16} \Omega$
  - Accurate low current sourcing, pA
  - No leakage errors due to mechanical switches
  - Includes software to automate measurements and calculate resistivity



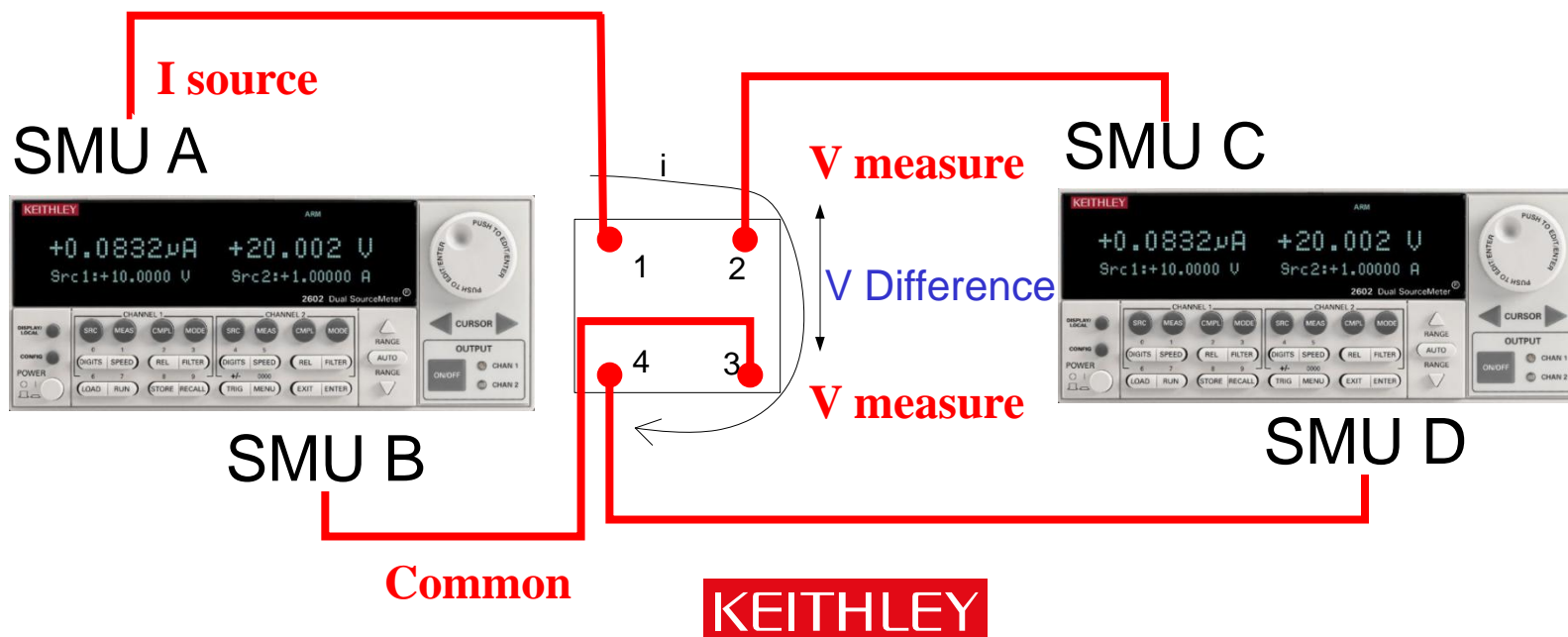
# Mid- to super-high resistance measurements (100 mΩ to 10 TΩ): Other options

- Option 2: Model 6514 Electrometers used as high impedance buffers



# Mid- to Super-High Resistance Measurements (100 mΩ to 10 TΩ): Other Options

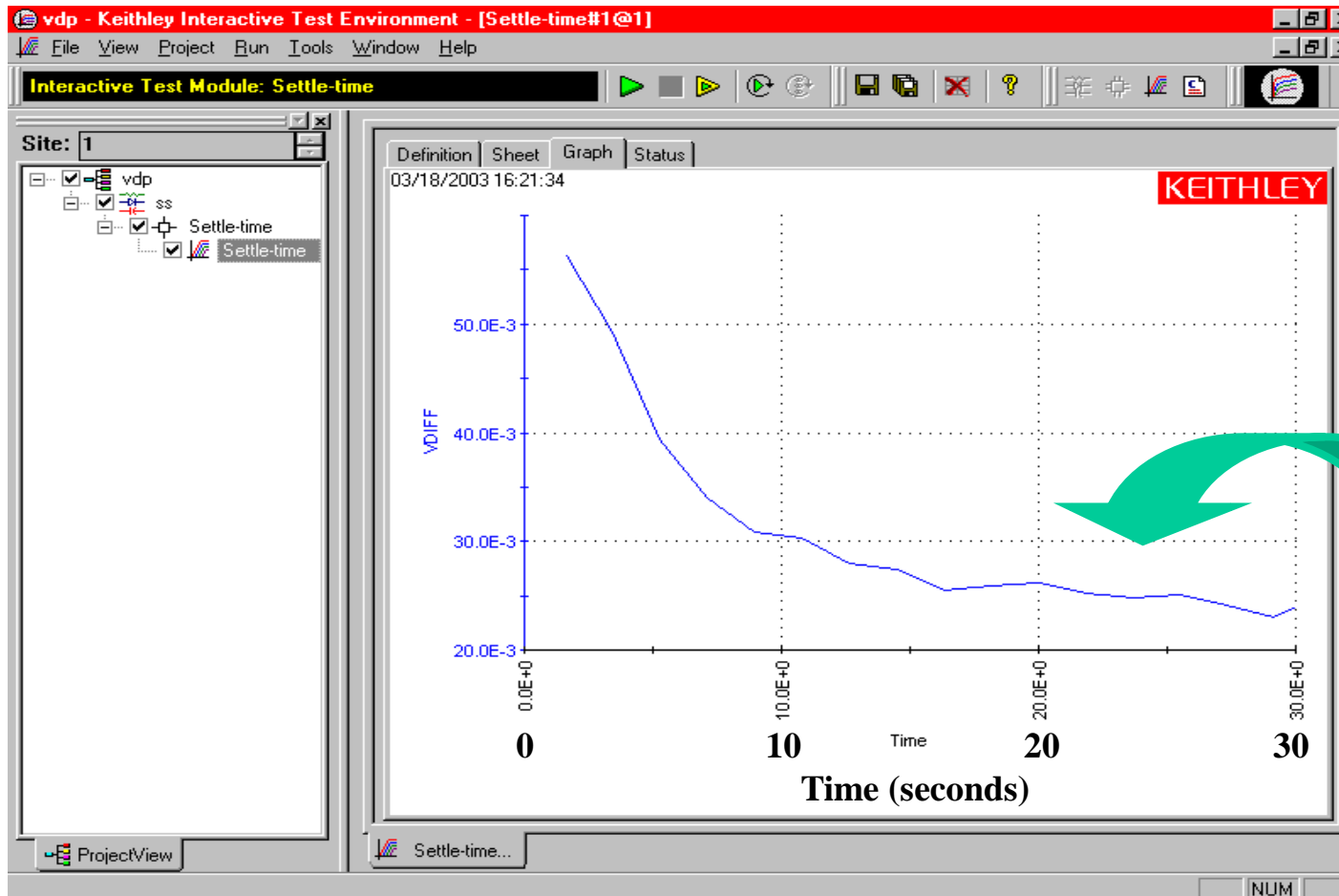
- **Option 3: Use 2 x 2636As SourceMeter Instruments**
  - Adds I-V sweep capability
  - Software options: ACS-Basic, TSP® Express, downloaded embedded tests scripts, or custom software (Services)
  - No switch needed



# Making Good Measurements on High Resistivity Materials

- Electrostatic shielding to minimize electrical interference
  - Shield the DUT and all sensitive circuitry
  - Use shielded cabling
  - Connect the shield to the low terminal of the system
- Use guarding to reduce the effects of leakage current in system
  - Guarded current source
  - Guarded voltmeters
  - Use triax cable instead of coax cable
- Allow sufficient settling time
  - Source  $I$  and measure  $V$  as a function of time to determine appropriate settling
  - A diamond sample can take 10 – 15 minutes for settling

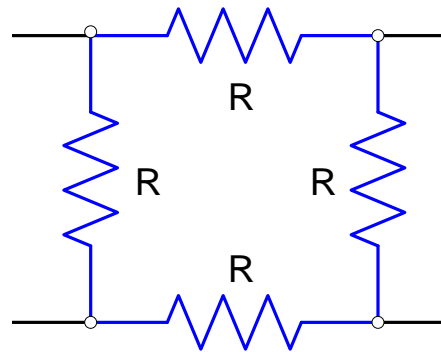
# Settling Time of a $10^{12}\Omega$ Resistance Sample

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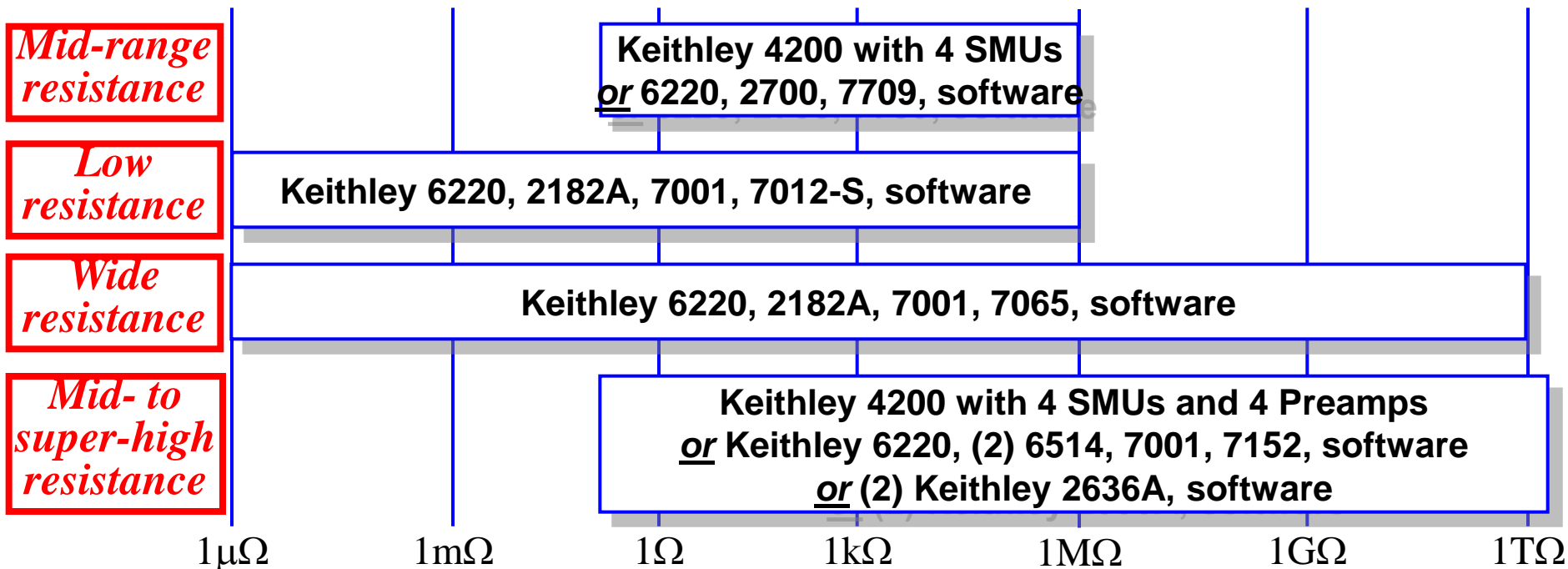
## Building Confidence in Your System

- Build a test structure using four resistors of equal value that are similar in magnitude to the resistance of the sample under test
- Have a known good sample characterized by a recognized laboratory



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# Overview of Keithley Offerings



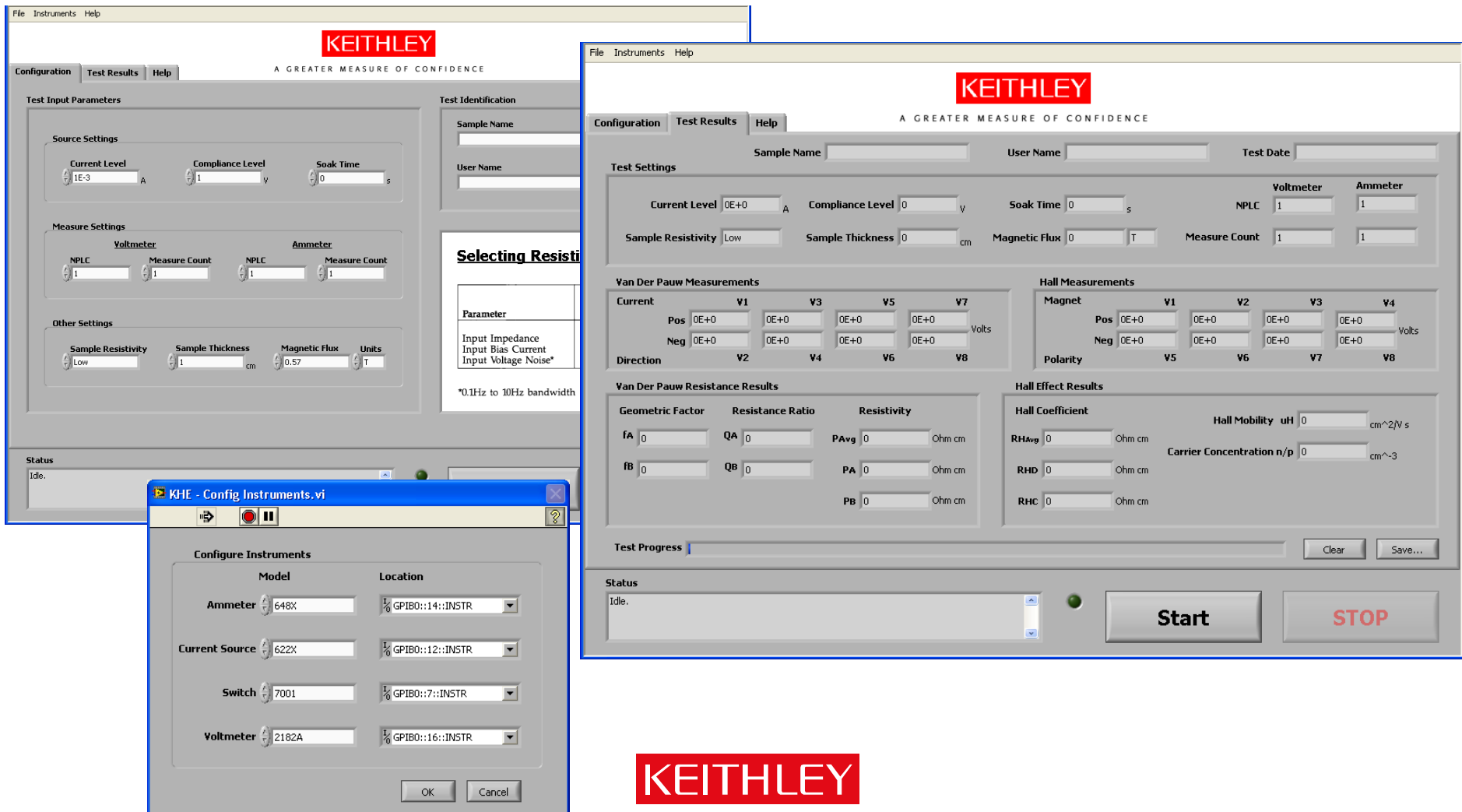
Sample Resistance ( $\Omega$ )

(actual selection depends on Total Resistance = Sample Resistance + Contact Resistance)

Sample Resistance  $\approx \rho/t$

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# Example Custom GUI from Keithley Software Services



## Additional Reference Material

- Application Note: Four-Probe Resistivity and Hall Effect Measurements with the Model 4200-SCS
  - <http://www.keithley.com/support/data?asset=15222>
- Low Level Measurements Handbook, Section 4.4
- Semiconductor Material and Device Characterization by Deiter Schroder
- 6220 Current Source Datasheet: <http://www.keithley.com/support/data?asset=15911>
- 2182A Nanovoltmeter: <http://www.keithley.com/support/data?asset=15912>
- 6514 Electrometer: <http://www.keithley.com/support/data?asset=387>
- 2000 DMM: <http://www.keithley.com/support/data?asset=359>
- 7001 Switch Mainframe: <http://www.keithley.com/support/data?asset=390>
- 7012-C 4x10 Matrix Card: <http://www.keithley.com/support/data?asset=393>
- 7152 Low Current Matrix Card: <http://www.keithley.com/support/data?asset=426>
- 7065 Hall Effect Switch Card: <http://www.keithley.com/support/data?asset=560>

## Contact Keithley with Your Questions

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